

INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(Not for submission under 37 CFR 1.99)</i>	Application Number	09836449
	Filing Date	2001-04-17
	First Named Inventor	Stephen J. Fonash
	Art Unit	2812
	Examiner Name	Richard A. Booth
	Attorney Docket Number	201009-007000

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<i>RJ</i>	1	BAE ET AL., "Characteristics of amorphous and polycrystalline silicon films deposited at 120 C by electron cyclotron resonance-enhanced chemical vapor deposition," J. Vac. Sci. & Technol. A16(3), May/June 1998, pp. 1912-1916.	<input type="checkbox"/>
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Examiner Signature	<i>Richard A. Booth</i>	Date Considered	<i>01/21/08</i>
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